

Supplementary materials for

# Increasing Efficiency of Hierarchical Nanostructured Heterojunction Solar Cells to 16.3% *via* Controlling Interface Recombination

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**Table S1.** Overview the efficiency of Si heterojunction nanostructure solar cells

<i>Institute</i>	$V_{oc}$ (mV)	$J_{sc}$ (mA/cm <sup>2</sup> )	FF (%)	Eff (%)	Year
General Electric-Global Research Center, New York	0.13	1.6	28	0.058	2007 [1]
Harvard University, Cambridge	0.26	N/A	55	3.4	2007 [2]
University of California, Berkeley	0.29	4.28	33	0.46	2008 [3]
The Pennsylvania State University	0.5	7.6	57	2.3	2010 [4]
Hanyang University	0.52	17.67	71.36	6.56	2010 [5]
Cornell University	0.59	26.4	69	10.8	2010 [6]
Stanford University	0.58	29.2	64.9	11	2011 [7]
University of California, Berkeley	0.59	31.1	66.4	12.2	2012 [8]
University of Texas at San Antonio	0.53	29.5	61.2	9.6	2013 [9]
Institute of Photonic Technology	0.53	26.46	73.4	10.0	2013 [10]
National Taiwan University	0.596	36.58	69.5	15.1	2013 [11]
Delft University of Technology	0.5	35.1	67	11.8	2014 [12]
<b><i>Nankai University*</i></b>	<b>0.611</b>	<b>37.1</b>	<b>71.7</b>	<b>16.3</b>	<b>2015</b>

**\* This work**  
**(Special interface engineering for solar cells)**

## Reference

- [1] Tsakalagos, L.; Balch, J.; Fronheiser, J.; Korevaar, B. A.; Sulima, O.; Rand, J. *Applied Physics Letters* **2007**, 91, (23), 2331-17.
- [2] Tian, B.; Zheng, X.; Kempa, T. J.; Fang, Y.; Yu, N.; Yu, G.; Huang, J.; Lieber, C. M. *Nature* **2007**, 449, (7164), 885-889.
- [3] Garnett, E. C.; Yang, P. *Journal of the American Chemical Society* **2008**, 130, (29), 9224-9225.
- [4] Kendrick, C. E.; Yoon, H. P.; Yuwen, Y. A.; Barber, G. D.; Shen, H.; Mallouk, T. E.; Dickey, E. C.; Mayer, T. S.; Redwing, J. M. *Applied Physics Letters* **2010**, 97, (14), 143108.
- [5] Jung, J.-Y.; Guo, Z.; Jee, S.-W.; Um, H.-D.; Park, K.-T.; Lee, J.-H. *Optics Express* **2010**, 18, (S3), A286-A292.
- [6] Lu, Y.; Lal, A. *Nano letters* **2010**, 10, (11), 4651-6.
- [7] Kim, D. R.; Lee, C. H.; Rao, P. M.; Cho, I. S.; Zheng, X. *Nano letters* **2011**, 11, (7), 2704-2708.
- [8] Gharghi, M.; Fathi, E.; Kante, B.; Sivoththaman, S.; Zhang, X. *Nano letters* **2012**, 12, (12), 6278-6282.
- [9] Pudasaini, P. R.; Ruiz-Zepeda, F.; Sharma, M.; Elam, D.; Ponce, A.; Ayon, A. A. *ACS applied materials & interfaces* **2013**, 5, (19), 9620-9627.
- [10] Jia, G.; Eisenhower, B.; Dellith, J.; Falk, F.; Thøgersen, A.; Ulyashin, A. *Journal of Physical Chemistry C* **2013**, 117, (2), 1091-1096.
- [11] Wang, H.-P.; Lin, T.-Y.; Hsu, C.-W.; Tsai, M.-L.; Huang, C.-H.; Wei, W.-R.; Huang, M.-Y.; Chien, Y.-J.; Yang, P.-C.; Liu, C.-W.; Chou, L.-J.; He, J.-H. *ACS Nano* **2013**, 7, (10), 9325-9335.
- [12] Isabella, O.; Vismara, R.; Ingenito, A.; Si, F. T.; Zeman, M., Light, Energy and the Environment, Canberra, 2014.12; Optical Society of America: Canberra, p PW3C.3.

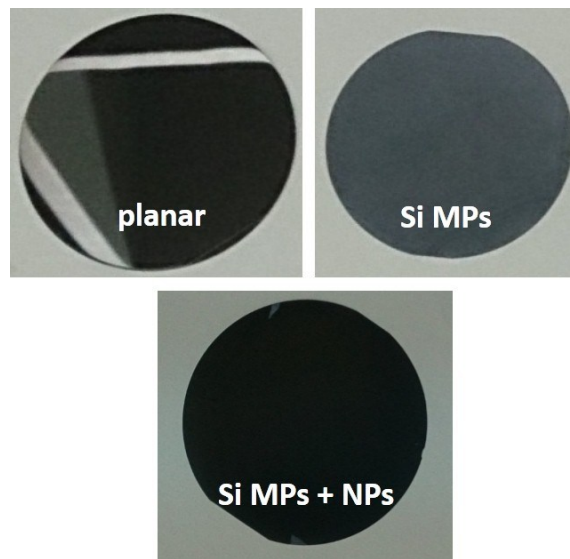
## Details of PECVD process parameters

**Table S2.** RF-PECVD system conditions for hydrogen plasma pre-treatment and i-a-Si:H films.

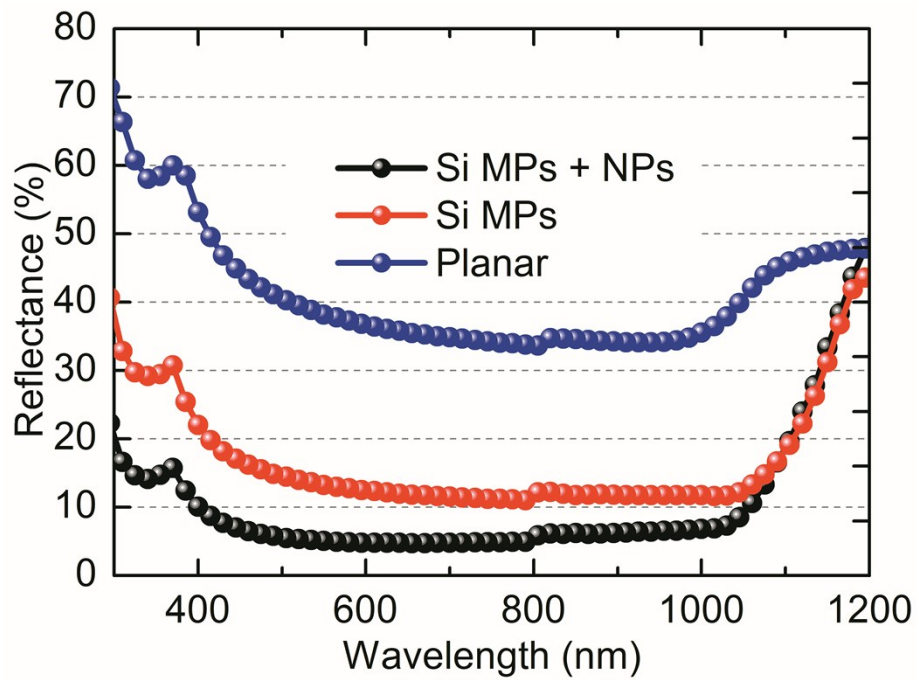
Process	$T_{dep}$ (°C)	H <sub>2</sub> (sccm)	SiH <sub>4</sub> (sccm)	Power density (mW/cm <sup>2</sup> )	Pressure (Torr)
H <sub>2</sub> -plasma treatment	140	50	-	8	2.2
i-a-Si:H	140	50	20	25	1

**Table S3.** Conditions for depositing the p- and n-type doped layer.

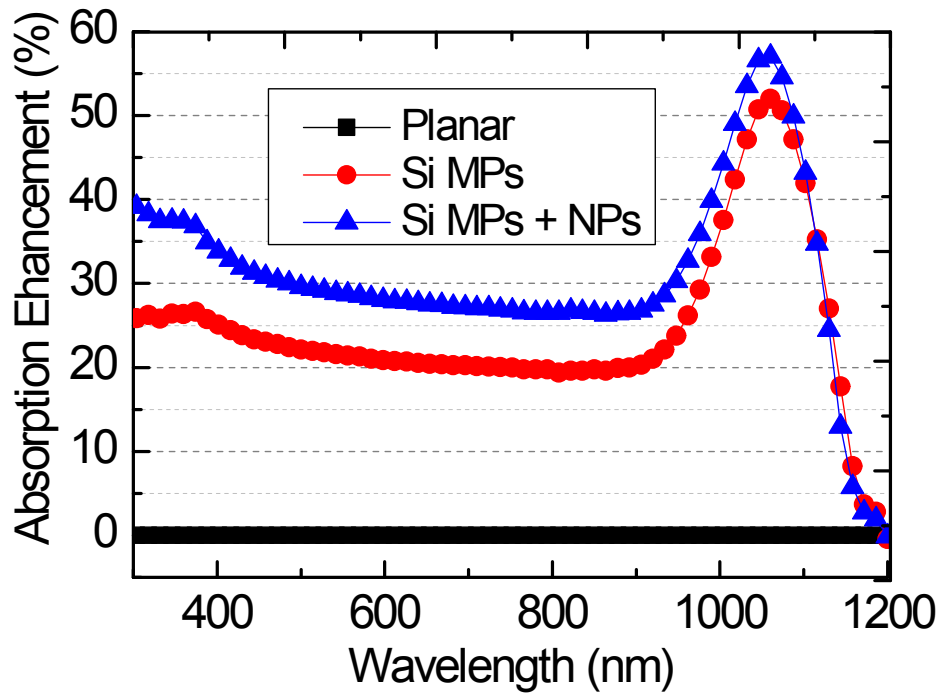
Layer	$P$ (mW/cm <sup>2</sup> )	$T_{dep}$ (°C)	SiH <sub>4</sub> (sccm)	TMB (sccm)	PH <sub>3</sub> (sccm)	H <sub>2</sub> (sccm)	$p$ (Torr)
p-a-Si:H	53	180	1	2	-	120	2
n-a-Si:H	53	180	2	-	2.5	180	1.3



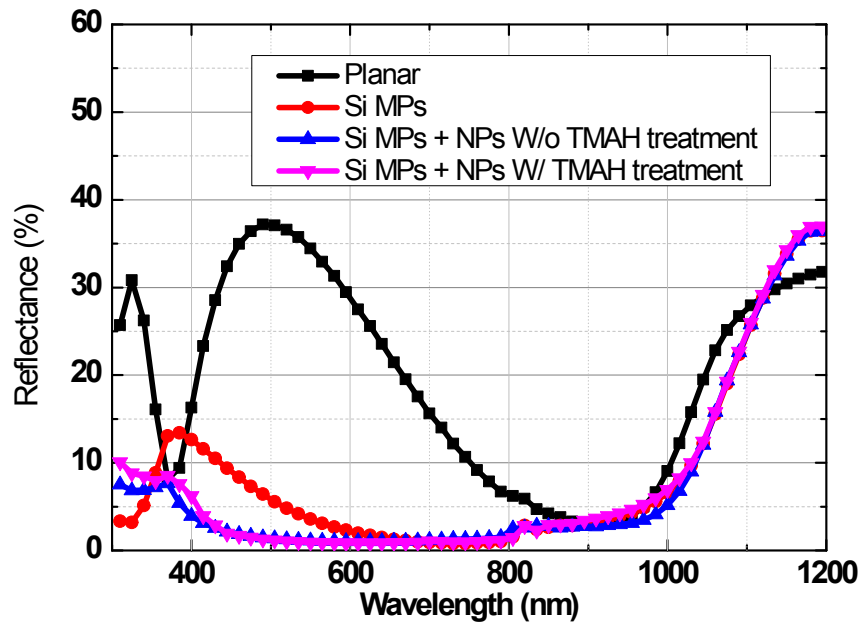
**Fig. S1.** Photographic image of structures planar, Si MPs, and Si MPs + NPs structure substrates.



**Fig. S2.** Total reflectance spectra of planar, Si MPs, and Si MPs + NPs structure substrates.



**Fig. S3.** The absorption enhancement for Si MPs and Si MPs + NPs substrates, compared with planar substrate.



**Fig. S4.** The total reflectance of the heterojunction solar cells based on Planar, Si MPs, Si MPs + NPs with treatment, and Si MPs + NPs without treatment substrates.